

Attorney's Docket No. P00743/70003

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant:

Stephen D. SENTURIA

8-22-02

Serial No .:

اسن 381,090,381

Filing Date:

March 4, 2002

For:

METHODS AND APPARATUS FOR WAVELENGTH-BASED OPTICAL

PROCESSING

Examiner:

Unassigned

Art Unit:

Confirmation No.

Commissioner for Patents Washington, D.C. 20231

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AUG 2 1 2002

Sir/Madam:

Technology Center 2600

Transmitted herewith for filing is/are the following document(s):

[X] Supplemental Information Disclosure Statement

[X] PTO Form 1449 With Cited References

[X] Return Post Card

If the enclosed papers are considered incomplete, the Mail Room and/or the Application Branch is respectfully requested to contact the undersigned collect at (617)720-3500, Boston, Massachusetts.

No check is enclosed. If it is determined that a fee is necessary, the fee may be charged to the account of the undersigned, Deposit Account No. 23/2825. A duplicate of this sheet is enclosed.

CERTIFICATE OF MAILING UNDER 37 C.F.R. §1.8(a)

I hereby certify that this document is being placed in the United States mail with first-class postage attached, addressed to the Commissioner for Patents, Washington, D.C. 20231 on August 5 2002.

Respectfully submitted,

Stephen D. SENTURIA

Jeffrey B. Powers

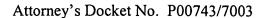
Registration No. 45,021

WOLF, GREENFIELD & SACKS, P.C.

600 Atlantic Avenue Boston, MA 02210 Tel. (617)720-3500

Attorneys for the Applicant(s)

Attorney's Docket No. P00743/7003





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SUPPLEMENTAL STATEMENT FILED PURSUANT TO THE DUTY OF DISCLOSURE UNDER 37 CFR §1.56, 1.97 AND 1.98

Sir:

Pursuant to the duty of disclosure under 37 C.F.R. §§1.56, 1.97 and 1.98, the Applicant requests consideration of this Information Disclosure Statement.

Compliance with 37 C.F.R. §1.97

This Information Disclosure Statement is being filed before the mailing date of a first Office Action on the merits in the above-identified case. No fee or certification is required.

Information Cited

The Applicant hereby makes of record in the above-identified application the information listed on the attached form PTO-1449 (modified). The order of presentation of the references should not be construed as an indication of the importance of the references.

REMARKS

Documents cited on the attached form PTO-1449 (modified) are enclosed unless otherwise indicated on the attached form PTO-1449 (modified). It is respectfully requested that:

1. The Examiner consider completely the cited information, along with any other information, in reaching a determination concerning the patentability of the present claims;

Art Unit:

- 2. The enclosed form PTO-1449 be signed by the Examiner to evidence that the cited information has been fully considered by the Patent and Trademark Office during the examination of this application;
- 3. The citations for the information be printed on any patent which issues from this application.

By submitting this Information Disclosure Statement, the Applicant makes no representation that a search has been performed, of the extent of any search performed, or that more relevant information does not exist.

By submitting this Information Disclosure Statement, the Applicant makes no representation that the information cited in the Statement is, or is considered to be, material to patentability as defined in 37 C.F.R. §1.56(b).

By submitting this Information Disclosure Statement, the Applicant makes no representation that the information cited in the Statement is, or is considered to be, in fact, prior art as defined by 35 U.S.C. §102.

Notwithstanding any statements by the Applicant, the Examiner is urged to form his own conclusion regarding the relevance of the cited information.

An early and favorable action is hereby requested.

CERTIFICATE OF MAILING UNDER 37 C.F.R. §1.8(a)

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Attorney's Docket No. P00743/70003

Respectfully submitted,

Stephen D. SENTURIA

Jeffrey/B. Powers
Registration No. 45,021

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Attorneys for the Applicant(s)

AUG 1 9 2002				
FOM PTO-1449/45 And B (Modified)	APPLICATION NO.: 10/090,381	ATTY. DOCKET NO.: P00743/70003		
INFORMATION DISCLOSURE	FILING DATE: March 4, 2002			
STATEMENT BY APPLICANT	APPLICANT: Stephen D	. SENTURIA		
Sheet 1 of 9	GROUP ART UNIT:	EXAMINER:		

Examiner's	Cite	U.S. Patent Doc	ument	Name of Patentee or Applicant of Cited	Date of Publication or of issue	
Initials #	No.	Number Kind Code		Document	of Cited Document MM-DD-YY	
		3,553,364		Lee	01/05/71	
		4,234,788		Palmer et al.	11/18/80	
		4,731,670		Allen et al.	03-15-1988	
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		5,022,745		Zayhowski et al.	06/11/91	
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		5,291,502		Pezeshki et al.	03/01/94	
		5,311,360		Bloom et al.	05-10-1994	
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	No.	Office/ Country	Number	Kind Code	Document (not necessary)	Cited Document MM-DD-YY	(Y/N)
		wo	98/41893	A1		09-24-1998	
		wo	91/02991	Al		03-07-1991	

OTHER ART - NON PATENT LITERATURE DOCUMENTS

Examiner's	Cite	Include name of the author (in CAPITAL LETTERS) title of the article (when appropriate), title of the	Translation
Initials #	No	item (book, magazine, journal, serial, symposium, catalog, etc.), date, relevant page(s), volume-issue	(Y/N)
		number(s), publisher, city and/or country where published.	
		MICROMECHANICAL LIGHT MODULATOR ARRAY FABRICATED ON SILICON, K.E. PETERSEN, IBM	
		Research Lab., Applied Physics Letters, Vol. 31, No. 8, 10/15/77, pp 521-523	

EXAMINER	DATE CONSIDERED

#EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

AU6 11	2002		•			
FORMATION	A and B (M	lodifie	d)	APPLICATION NO.:	10/090,381	ATTY. DOCKET NO.: P00743/70003
INFORMATION DISCLOSURE STATEMENT BY APPLICANT				FILING DATE: March 4, 2002		
				APPLICANT: Stephen D. SENTURIA		
Sheet	2	of	9	GROUP ART UNIT:		EXAMINER:

Examiner's Initials #	Cite	U.S. Patent Document		Name of Patentee or Applicant of Cited	Date of Publication or of issue
	No.	Number	Kind Code	Document	of Cited Document MM-DD-YY
		5,392,151		Nelson	02/21/95
 -		5,396,066		Ikeda et al.	03/07/95
		5,459,610		Bloom et al.	10-17-1995
		5,561,523		Blomberg et al.	10/01/96
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		Office/ Country	Number	Kind Code	Document (not necessary)	Cited Document MM-DD-YY	(Y/N)
		WO	01/11394	A1		02-15-2001	
		wo	01/11419	A2	Godil et al.	15-02-2001	
		WO	01/11410	A 1	Thackara et al.	02/15/01	
		wo	01/11396	A 1		02-15-2001	

OTHER ART - NON PATENT LITERATURE DOCUMENTS

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		number(s), publisher, city and/or country where published.	
		MINIATURE FABRY-PEROT INTERFEROMETERS MICROMACHINED IN SILICON FOR USE IN OPTICAL FIBER WDM	
		SYSTEMS, J.H. JERMAN et al., IEEE 1991 372, International Conf. On Solid-State Sensors and	
L		Actuators 1991, pp 372-375	

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AUG	9 2002							
FOR PTO	0-144946 and B (M	odifie	d)	APPLICATION NO.:	10/090,381	ATTY. DOCKET NO.: P00743/70003		
	FORMATION			FILING DATE:	FILING DATE: March 4, 2002			
STATEMENT BY APPLICANT				APPLICANT:	APPLICANT: Stephen D. SENTURIA			
Sheet	3	of	9	GROUP ART UNIT:		EXAMINER:		

Examiner's Initials #	Cite	te U.S. Patent Document		Name of Patentee or Applicar	Date of Publication or of issue		
	No.	Number	Kind Code	Document		of Cited Doc MM-DD-	
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		5,781,670		Deacon et al.			07-14-1998
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		5,808,797		Bloom et al.	RECEI	VED	09-15-1998
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		5,841,579		Bloom et al.	HUU D I	2002	11-24-1998

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10-10-2001

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		Office/ Country	Number	Kind Code	Document (not necessary)	Cited Document MM-DD-YY	Document (Y/N)
		wo	01/42825	Al	Gutin	06/14/01	_,
		EP	1 122 577	A2		08-08-2001	

OTHER ART -- NON PATENT LITERATURE DOCUMENTS

Examiner's Cite Initials # No	Cite No	Include name of the author (in CAPITAL LETTERS) title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, relevant page(s), volume-issue number(s), publisher, city and/or country where published.	
· · · · · ·		Solgaard et al., "Deformable grating optical modulator," Optics Letters, Vol. 17, No. 9, May 1, 1992, pgs. 688-690.	
		Goossen et al., "Silicon Modulator Based on Mechanically-Active Anti-Reflection Layer with 1 Mbit/sec Capability for Fiber-in-the-Loop Applications," <u>IEEE Photonics Technology Letters</u> , Vol. 6, No. 9, September 1994, pgs. 1119-1121.	
		SPECTRALLY SELECTIVE GAS CELL FOR ELECTROOPTICAL INFRARED COMPACT MULTIGAS SENSOR, MELÉNDEZ et al., Elsevier Science S.A., Sensors and Actuators 46-47 (1995) 417-421	
		SILICON MICROMACHINED INFRARED SENSOR WIHT TUNABLE WAVELENGTH SELECTIVITY FOR APPLICATION IN INFRARED SPECTROSCOPY, D. ROSSBERG., Elsevier Science S.A., Sensors and Actuators 46-47 (1995) 413-416	
		CONTINUOUS-MEMBRANE SURFACE-MICROMACHINED SILICON DEFORMABLE MIRROR, BIFANO et al., Soc. of Photo-Optical Ins. Eng. Opt. Eng. 36(5) May 1997, pp 1354-1360	

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*a copy of this reference is not provided as it was previously cited by or submitted to the office in a prior application, Serial No. ________, filed _______, and relied upon for an earlier filing date under 35 U.S.C. 120 (continuation, continuation-in-part, and divisional applications).

[NOTE - Must provide a copy of any patent, publication, other information listed, even if it was previously submitted to, or cited by, the U.S. Patent Office in an earlier application, unless the earlier application is identified by the IDS and is relied upon for an earlier filing date under 35 U.S.C. §120, and the copy was provided in the earlier application.]

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1 143 287

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AUG 1 9	3002 E				•			
FORMPIO	A and B (M	odifie	d)	APPLICATION NO.:	10/090,381	ATTY. DOCKET NO.: P00743/70003		
INFORMATION DISCLOSURE				FILING DATE:	FILING DATE: March 4, 2002			
ST	ATEMENT B	Y A	PPLICANT	APPLICANT:	Stephen D.	SENTURIA		
Sheet	4	of	9	GROUP ART UNIT:		EXAMINER:		

Examiner's Initials #	Cite	U.S. Patent Doc	ument	Name of Patentee or Applicant of Cited	Date of Publication or of issue of Cited Document MM-DD-YY 12-08-1998 02-09-1999	
	No.	Number	Kind Code	Document		
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		5,870,221		Goossen		
		5,905,571		Butler et al.	05/18/99	
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		5,920,418_		Shiono et al.	07-06-1999	
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		Office/ Country	Number	Kind Code	Document (not necessary)	Cited Document MM-DD-YY	Translation (Y/N)	

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Initials #	No	item (book, magazine, journal, serial, symposium, catalog, etc.), date, relevant page(s), volume-issue	
		number(s), publisher, city and/or country where published.	
		MOCRO-ACTUATED MIRRORS FOR BEAM STEERING, GUSTAFSON et al., SPIE- Society of Photo-Optical Instrumentation Engineering, Vol. 3008, 1997, pp 90-99	
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		INVESTIGATION OF THE MAXIMUM OPTICAL POWER RATING FOR A MICRO-ELECTRO-MECHANICAL DEVICE, BURNS et al., Internat'l Conf. On Solid-State Sensors and Actuators 06/16/97-06/19/97, pp 335-338	

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AUG 1	9 2002 E						
FORMAT	and B (M	lodifie	d)	APPLICATION NO.:	10/090,381	ATTY. DOCKET NO.: P00743/70003	
IN	FORMATION	DIS	CLOSURE	FILING DATE:	FILING DATE: March 4, 2002		
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Initials #	No.	Number	Kind Code	Document		
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		5,969,848		Lee et al.	10/19/99	
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		6,144,481		Kowarz et al	11-07-2000	
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- <u>-</u> -		6,175,443	B1	Aksyuk et al.	01-16-2001	
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		number(s), publisher, city and/or country where published.	
		NONLINEAR FLEXURES FOR STABEL DEFLECTION OF AN ELECTROSTATICALLY ACTUATED MICROMIRROR,	
		BURNS et al., Air Force Institute of Technology, Dept. of Ele and Comp Eng., Wright-Patterson AFB,	
	.	Ohio, SPIE Vol. 3226, 1997, pp 125-136	
		SYNTHETIC SPECRA; A TOOL FOR CORRELATION SPECTROSCOPY, SINCLAIR et al., Applied Optics, Vol.	
		36, No. 15 05/20/97, pp 3342-3348	

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AUG 19	MOL E		•				
PORM PTO)-1449 and B (M	odifie	i)	APPLICATION NO.: 10/090,38	ATTY. DOCKET NO.: P00743/70003		
PARTO-1449 and B (Modified) THE ORMATION DISCLOSURE				FILING DATE: March 4, 2002			
ST	ATEMENT B	Y Al	PPLICANT	APPLICANT: Stephen I	D. SENTURIA		
Sheet	6	of	9	GROUP ART UNIT:	EXAMINER:		

Examiner's	Cite	U.S. Patent Doc	ument	Name of Patentee or Applicant of Cited	Date of Publication or of issue
Initials #	No.	Number	Kind Code	Document	of Cited Document MM-DD-YY
		6,233,087	B1	Hawkins et al.	05-15-2001
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Examiner's Cite Initials # No						
		number(s), publisher, city and/or country where published.				
		SYNTHETIC INFRARED SPECRA, SINCLAIR et al., Optical Society of America, Optical Letters, vol. 22, No. 13 07/01/97, pp 1036-1038				
		ELECTROSTATIC EFFECTS IN MICROMACHINED ACTUATORS FOR ADAPTIVE OPTICS, HORENSTEIN, et al., Dept. of Aerospace and Mech. Eng., BU, Boston, MA, J. of Electrostatics, pp 69-81 (1997)				
		ANALYSIS OF GRATING LIGHT VALVES WITH PARTIAL SURFACE ELECTRODES, FURLANI et al., J. Appl. Phys. 83 (2), 01/15/98, American Institute of Physics, pp 629-634				
		POSITIONING, CONTROL, AND DYNAMICS OF ELECTROSTATIC ACTUATORS FOR USE IN OPTICAL AND RF SYSTEMS, E.S. HUNG, 08/21/98 thesis Massachusetts Institute of Technology, 107 pages				
		OPTICAL PHASE MODULATION USING A REFRACTIVE LENSLET ARRAY AND MICROELECTROMECHANICAL DEFORMABLE MIRROR, COWAN et al., AFRL/MLP, Optical Engineering, Vol. 37 No. 12, 12/123/98, pp 3237-3247				
-		LEVERAGED BENDING FOR FULL-GAP POSITIONING WITH ELECTROSTATIC ACTUATION, E.S. HUNG et al., MIT, Solid-State Sensor and Actuator Workshop Hilton Head Island, SC 06/08/98-06/11/98 pp 83-86				

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AUG 1 9 2	ON ALL SCORE		•		•	
BORM PTO	A and B (M	odifie	d)	APPLICATION NO.:	10/090,381	ATTY. DOCKET NO.: P00743/70003
IN:	FORMATION	DIS	CLOSURE	FILING DATE:	March 4, 200)2
ST	ATEMENT B	Y Al	PPLICANT	APPLICANT:	Stephen D.	SENTURIA
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Initials #	No.	Number	Kind Code	Document	of Cited Document MM-DD-YY	
		6,282,213	B1	Gutin et al. BECEIV	ED 08-28-2001	
		6,284,560	Bl	Jech, Jr. et al.	09-04-2001	
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Examiner's Initials #	Cite No	Include name of the author (in CAPITAL LETTERS) title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, relevant page(s), volume-issue number(s), publisher, city and/or country where published.	Translation (Y/N)
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